



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Koichiro Tanaka
Serial No. : 09/842,797
Filed : April 27, 2001
Title : METHOD OF FABRICATING SEMICONDUCTOR DEVICE

Art Unit : 2822
Examiner : Maria F. Guerrero

MAIL STOP AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Applicants request consideration of the references listed on the attached PTO-1449 form. Under 37 C.F.R. § 1.98 (a)(2)(ii), only copies of foreign patent documents and/or non-patent literature are enclosed. Copies of any U.S. patents or U.S. patent application publications can be provided upon request.

This statement is being filed after a first Office action on the merits, but before receipt of a final Office action or a Notice of Allowance. A check for \$180 in payment of the late submission fee of §1.17(p) is enclosed. Please apply any other charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date: 3/23/05

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Substitute Form PTO-1449 (Modified) Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR §1.98(b))	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 12732-034001	Application No. 09/842,797
	Applicant Koichiro Tanaka		
	Filing Date April 27, 2001	Group Art Unit 2822	

U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA	4,439,245	03/27/1984	WU			01/25/1982
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
	AQ	Hayashi et al., "FABRICATION OF LOW-TEMPERATURE BOTTOM-GATE POLY-SI TFTS ON LARGE-AREA SUBSTRATE BY LINEAR-BEAM EXCIMER LASER CRYSTALLIZATION AND ION DOPING METHOD," IEDM '95; Technical Digest of International Electron Devices Meeting, 33.3.1 - 33.3.4, pp. 829-832, December 10-13, 1995.
	AR	
	AS	
	AT	

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	